


Fig. 1


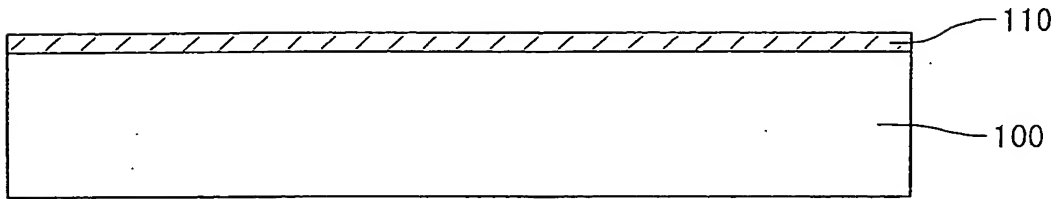


図2

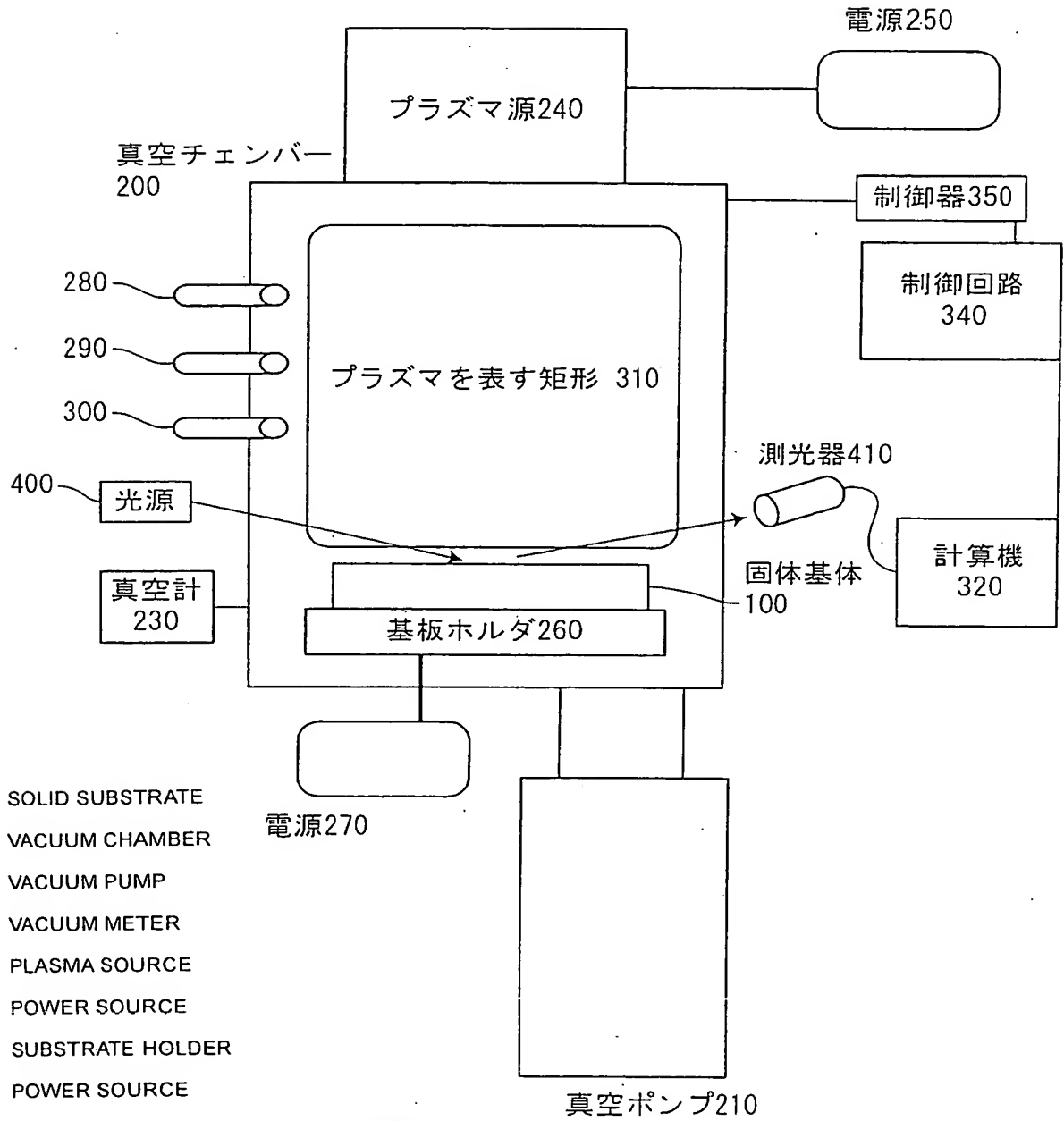
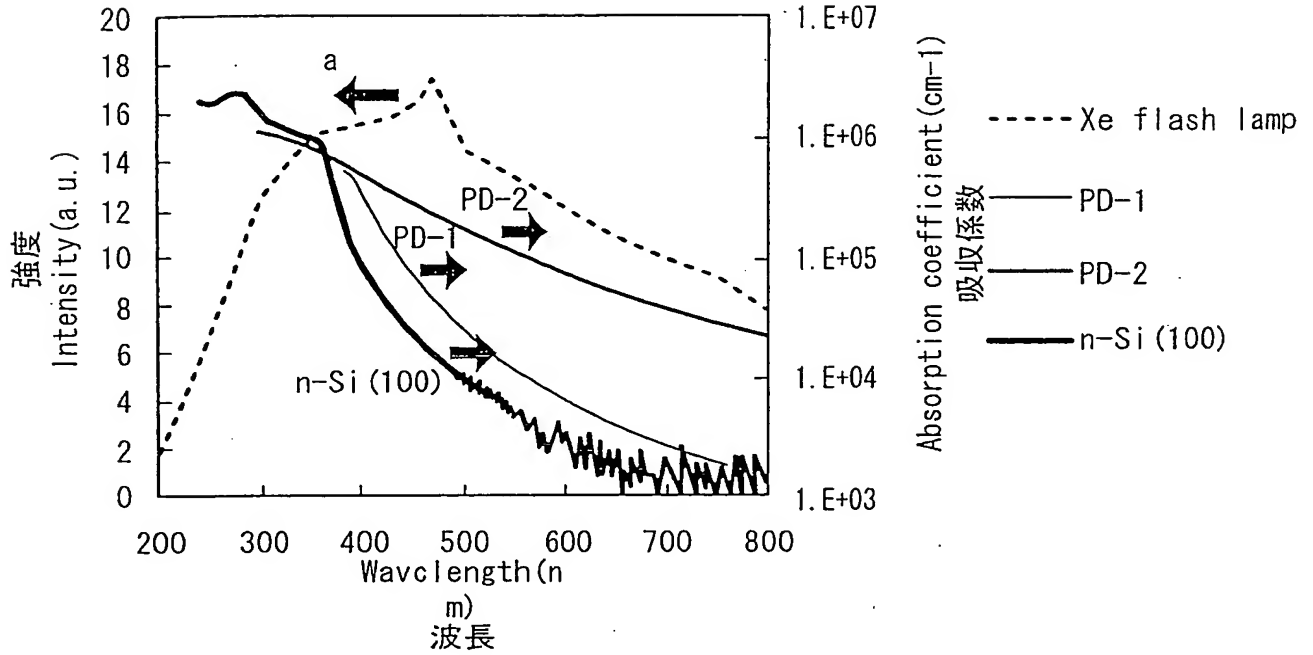


FIG. 2

- 100 SOLID SUBSTRATE
- 200 VACUUM CHAMBER
- 210 VACUUM PUMP
- 230 VACUUM METER
- 240 PLASMA SOURCE
- 250 POWER SOURCE
- 260 SUBSTRATE HOLDER
- 270 POWER SOURCE
- 310 SQUARE REPRESENTATIVE OF PLASMA
- 320 COMPUTER
- 340 CONTROL CIRCUIT
- 350 CONTROLLER
- 410 PHOTOMETER

~~Fig. 3~~ 3 Fig. 3



~~Fig. 4~~ 4 Fig. 4

